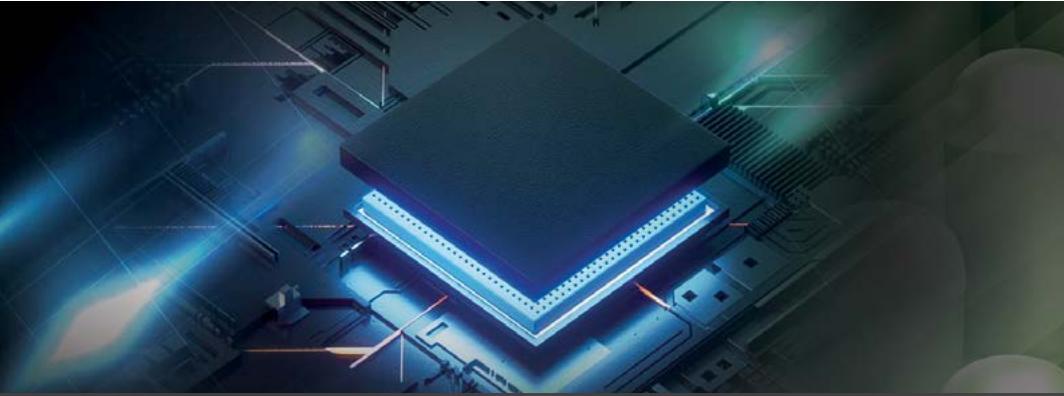




**Camtek**  
See Beyond



Best in Class, Multi-Sensor Metrology

# MICROPROF<sup>®</sup> AP

**MicroProf<sup>®</sup> AP** is the most versatile metrology tool on the market. Its multi-sensor setup and software packages provide metrology data throughout Advanced Packaging processes.

- PI and PR film thickness and opening
- CD and overlay
- TSV metrology, fill monitoring, trenches
- Flatness and uniformity after CMP
- Copper erosion and dishing (Hybrid Bonding)
- UBM height and roughness
- RDL thickness, width and roughness
- Bump and nail height, diameter and coplanarity
- Bow and stress
- Carrier, adhesive, bonded wafer thickness and TTV



### 3D Metrology

|  |  |
|--|--|
| Metrology Capabilities                   | <ul style="list-style-type: none"><li>• Customizable for any semiconductor metrology requirements by multi-sensor setup</li><li>• Addresses all metrology requirements that come with advanced packaging technology</li></ul>  |
| Wafer Handling Capabilities              | <ul style="list-style-type: none"><li>• Fast, safe and precise wafer handling</li><li>• Wafer handling and chucks are customizable to any kind of wafer type and size (300, 200 or 150 mm)</li><li>• Three-point or vacuum wafer positioning</li><li>• Optimized for high throughput with dual loadports, Pre-aligner and RFID Reader</li><li>• Optional add-ons for open-cassette handling (150 or 200 mm wafers), Bridge tool option (two wafer sizes in one tool), Edge grip handling option etc.</li><li>• Film frame wafer handling available</li></ul> |
| EFEM Enclosure                           | <ul style="list-style-type: none"><li>• ISO class 3 clean room conformal housing</li><li>• 2 filter fan units (FFU), one for handling and one for metrology area</li></ul>   |
| Metrology Software Acquire Automation XT | <ul style="list-style-type: none"><li>• Highly customizable software for fully automated semiconductor metrology</li><li>• Optimized for precision as well as throughput</li><li>• Tailored control for each sensor type</li><li>• Tailored evaluation for any measurement task required</li><li>• Trans-machine controls and settings via recipes</li></ul>   |